

APPLICATION DATA SHEET

Electronic Version v14

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Title of Invention	METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	
Application Type: regular, utility		
Attorney Docket Number: 36280		
Correspondence address:		
Customer Number: 000116 *000116*		
Priority Data:		
Doc.No: 2002-336415; Country - JP; Date: 2002-11-20 us-priority-claimed		
Doc.No: 2002-336416; Country - JP; Date: 2002-11-20 us-priority-claimed		
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